

Special Issue

Thin Film Deposition: From Fundamental Research to Applications

Message from the Guest Editors

Development in thin film deposition technologies has allowed the accelerated increase in almost all areas of science and technology we see today. The increasing demand for miniaturized devices and nanotechnology has motivated researchers to find new ways to synthesize or improve all kinds of thin film material systems using many physical and chemical thin film deposition techniques. This Special Issue is focused on publishing scientific research papers and review articles that discuss fundamental thin film research:

- Synthesis techniques: novel studies on thin film deposition techniques, such as advances in pulsed laser deposition, sputtering, chemical vapor deposition, and sol-gel, among others;
- Characterization: study of physical and chemical properties of different types of thin film materials;
- Applications: Experiments applying thin films in different fields of science;
- Simulation and theoretical calculations: studies on theory or simulation around specific properties or applications of thin films.

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Message from the Editor-in-Chief

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